

ABSTRACT

The present disclosure discloses an annular liner apparatus, a liner, a process chamber, and semiconductor process equipment. The annular liner apparatus is used in a process chamber and includes a first annular liner, a cylindrical liner, and a second annular liner. The first annular liner is connected to a first end of the cylindrical liner, and the second annular liner is connected to a second end of the cylindrical liner. The cylindrical liner is expandable and retractable along the axial direction of the cylindrical liner. This solution addresses the problem of poor shielding caused by poor grounding connection in the liner of the process chamber in related technologies.